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# An Improved Algorithm for Drift Diffusion Transport and Its Application on Large Scale Parallel Simulation of Resistive Random Access Memory Arrays

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**ABSTRACT** A hybrid finite volume–finite element method which can avoid overestimation of volume shared by each vertex in the meshing grid is proposed to solve the diffusive transport governed continuity equation. The simulation results demonstrate that the improved algorithm can eliminate unphysical distortions as compared to the conventional Scharfetter Gummel method. Based on the proposed algorithm, a parallel-computation simulator is developed for large-scale electrothermal simulation of resistive random access memory (RRAM) arrays, in which the domain decomposition method and J parallel adaptive unstructured mesh applications infrastructure are adopted. The validity, speedup, and scalability of the parallel simulator are investigated on the TianHe-2 supercomputer. Based on the simulated results, the electrothermal characteristics and reliability analysis of large-scale RRAM arrays are investigated in detail.

**INDEX TERMS** Domain decomposition method (DDM), drift diffusion, electrothermal modeling and simulation, finite element method (FEM), finite volume method (FVM), reliability, resistive random access memory (RRAM), thermal crosstalk.

### I. INTRODUCTION

Physically, ion migration in resistive random access memory, carrier transport in conventional semiconductor devices, or other advection-diffusion transport phenomena can be described by the drift-diffusion equation [1], [2]. Owing to the advection-diffusion feature, strong nonlinearity, and mixed nature, the spatial discretization of the drift-diffusion equation is a crucial issue. Some early attempts have been made to discretize this equation using classical finite element method (FEM) and finite difference (FD) scheme [3]. However, critical mesh size, as well as huge computing source, is usually required in these methods. Particularly, divergence often takes place when they are used to solve advection-dominated problem. To handle this limitation, a series of discretization schemes such as quasi-Fermi FEM [2], [4], Scharfetter-Gummel (SG) method [5], [6], Streamline Upwinding Petrov Galerkin method (SUPG) [7], [8], Finite Box Integration SG (FBSG) method [8], and divergence free method [7]

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have been proposed to discrete the drift-diffusion equation. Among them, the FBSG is the most popular adopted in commercial software, such as COMSOL, TCAD, and GSS [9], [10]. However, its accuracy and convergence highly depend on the quality of grid meshes, and it has inherent cross-winding effects for 2D and 3D problems due to the current density for integration fixed along the cell edges [3].

On the other hand, some modified methods such as the Petrov Galerkin FEM and parameter-free stabilized FEM have been proposed to solve 2D or 3D advection-diffusion problems [11]–[13]. Here, we develop a hybrid algorithm based on the finite volume-finite element (FVFEM) and SG methods. It allows to more effectively solve the drift-diffusion transport problem in electronic devices, including ion migration in RRAMs and diffusive carrier transport in semiconductor devices. The performance of the improved algorithm is examined and compared to previous algorithms.

In addition, a numerical scheme consisting of FVFEM-SG method and FEM is developed to analyze electrothermal coupling phenomena in large scale RRAM arrays, since self-heating becomes a significant issue as integration density increases and can lead to reliability problems, including performance degradation or even breakdown [14]–[16]. Inherently, the electrothermal processes are coupled together, making the simulation much more complicated, timeconsuming, and often beyond the capability of a personal computer (PC). To the best of the authors' knowledge, no work has been done for the simulation of large scale RRAM array [17]–[20]. Hence, a high-performance parallel simulation strategy is urgently needed to help solve this large scale multiphysics problem. Benefiting from the development of domain decomposition method (DDM), the capability of modeling and simulation of large-scale problems has been upgraded significantly [22]–[24]. Here, the J parallel adaptive unstructured mesh applications infrastructure (JAUMIN) and DDM based double-level parallel scheme proposed in [25] is employed for multiphysics problem.

The paper is organized as follows. In Section II, an improved algorithm is introduced at first. Then, the physical model of RRAM, numerical discretization scheme and parallel approach are presented in Section III. In Section IV, the parallel simulator is evaluated and then utilized to study the electrothermal characteristics of RRAM arrays. Some conclusions are finally drawn in Section V.

### **II. ALGORITHM DEVELOPMENT**

The continuity equation for diffusive transport process can be expressed as

$$\begin{cases} \nabla \cdot \overrightarrow{J} = \frac{\partial n}{\partial t} + R\\ n = n_d \mid_{\Gamma_D} \\ \overrightarrow{J} \cdot \overrightarrow{n} = h \mid_{\Gamma_n} \end{cases}$$
(1)

where n is the particle concentration which can be electron, hole in semiconductor, or oxygen vacancy in RRAM and so on, R is the recombination/generation rate,  $n_d$  is the Dirichlet boundary condition, h is the Neumann boundary condition, and  $\Gamma_D$  and  $\Gamma_N$  represent the Dirichlet and Neumann boundary, respectively. The drift-diffusion current density  $\vec{J}$  is given as

$$\vec{J} = \mu_n n \vec{E} + D_n \nabla n \tag{2}$$

where  $\mu_n$  is the mobility,  $D_n$  is the diffusion coefficient, respectively, and  $\vec{E}$  is the electric field intensity. In (2),  $\mu_n n \vec{E}$  and  $D_n \nabla n$  denote the drift and diffusion components, respectively.

When applying the FBSG to integrate the left-hand side of equation (1), the control volume shared by each vertex is determined by the circumcenter and center of each edge, as shown in Fig. 1(a). It is known that the circumcenter of an obtuse triangle lies outside the element, which results in an overestimation of the area shared by the vertex. In this context, it introduces unphysical disturbances to the algorithm that results in instability [3]. By contrast, the control volume for each vertex in the improved method is determined by the inner and edge centers, which guarantees that the volume is always inside the element, as shown in Fig. 1(b).



**FIGURE 1.** The control volume cell  $\Omega_i$  around vertex  $v_i$  for triangle meshing grid in (a) FBSG and (b) the improved method which is named as FVFEM-SG.

Different from the FBSG, the outward normal current density of a finite volume cell  $\Omega_i$  for the improved method must be treated carefully, since the current along each edge of a triangle element is no longer perpendicular to the outside surface of the volume cell  $\Omega_i$ . As a remedy, Nedelec edge basis space is employed to extract the current density at midpoint of each segment in  $\Omega_i$  by interpolation. The implementation of the improved method over control volume cell  $\Omega_i$  are addressed below.

The governing equation (1) is integrated over the volume cell  $\Omega_i$ 

$$\frac{1}{q} \int_{\Omega i} \nabla \cdot \vec{J} d\Omega = \int_{\Omega i} \frac{\partial n}{\partial t} d\Omega + \int_{\Omega i} R d\Omega$$
(3)

The Divergence theorem is applied to the left-hand side of (3) to obtain its 'weak' form, i.e.,

$$\frac{1}{q} \int_{\partial \Omega_i} \left( \vec{J} \cdot \vec{n} \right) \mathrm{d}S = \int_{\Omega_i} \frac{\partial n}{\partial t} \mathrm{d}\Omega + \int_{\Gamma N} h \mathrm{d}S + \int_{\Omega_i} R \mathrm{d}\Omega \qquad (4)$$

where  $\partial \Omega_i$  is the boundary of  $\Omega_i$ . By involving the standard Lagrangian basis {*N*} [26], the particle density within each

mesh element can be expanded as

$$n = \sum_{m \in \Omega_{\text{tri}} \cup \Gamma_N} n_m N_m + \sum_{m \in \Gamma_D} n_{d,m}(t) N_m$$
(5)

where  $m \in \Omega_{\text{tri}} \cup \Gamma_N$  denotes that the vertex  $v_m$  is in the interior of calculated domain or on the Neumann boundary,  $m \in \Gamma_D$  denotes that the vertex  $v_m$  belongs to the Dirichlet boundary, and  $n_{d,m}(t)$  is the time-dependent Dirichlet boundary value at the vertex  $v_m$ . As shown in Fig. 1(b), the control volume cell around the vertex  $v_i$  is composed of five parts belonging to five different mesh grids. To describe the problem more clearly, the integration over the part in mesh cell  $\Delta_{ijo}$  will be elaborated in the following.

With the consideration of the upwind effect, the current density  $\vec{J}$  described in (2) should be modified to SG formulation at each edge of the mesh cell. The SG formulation along the edge  $e_{ij}$  is expressed as

$$\left|\vec{J}_{ij}\right| = \frac{\mu_n E_{ij}}{2} \left(n_j \left[\coth\left(a_{ij}\right) + 1\right] - n_i \left[\coth\left(a_{ij}\right) - 1\right]\right) \quad (6)$$

where  $a_{ij}$  is the Reynolds number along the edge  $e_{ij}$ , and it can be calculated by  $a_{ij} = \mu_n l_{ij} E_{ij} / (2D_n)$ .  $l_{ij}$  is the length of edge  $e_{ij}$ , and  $E_{ij}$  is the electric field intensity along edge  $e_{ij}$ .

As mentioned above, the edge current is no longer perpendicular to the adjacent segment of boundary  $\partial \Omega_i$  in the proposed FVFEM-SG. To get the outward norm, the Nedelec edge basis space is employed to interpolate the upwind edge current in (6) to the center of adjacent segment of boundary  $\partial \Omega_i$  by [26]

$$\vec{J} = \sum_{e_{mp} \in E\left(\Delta_{ijo}\right)} \left| \vec{J}_{pm} \right| \cdot \vec{W}_{pm} \tag{7}$$

By substituting (5)-(7) into (4), the integration over the area  $\Delta_{ijo} \cap \Omega_i$  can be obtained as

$$\sum_{m \in \Delta_{ijo}} \frac{\partial n_m(t)}{\partial t} \int_{\Delta_{ijo} \cap \Omega_i} N_m d\Omega$$
  
$$- \sum_{e_{pm} \in E(\Delta_{ijo})} \frac{\mu_n E_{pm}}{2} \left( n_m \left[ \coth\left(a_{pm}\right) + 1 \right] - n_p \left[ \coth\left(a_{pm}\right) - 1 \right] \right)$$
  
$$\cdot \int_{\Delta_{ijo} \cap \partial \Omega_i} \vec{W}_{pm} \cdot \vec{n} dS = - \int_{\Gamma N} h dS - \int_{\Delta_i jo} \Omega_i R d\Omega \qquad (8)$$

Although the second term in the left-hand side of (8) is over the edges, it operates on the node degree of freedoms. Therefore, (8) can be further simplified by rewriting the second term as double sum, i.e.,

$$\sum_{m \in \Delta_{ijo}} \frac{\partial n_m(t)}{\partial t} \int_{\Delta_{ijo} \cap \Omega_i} N_m d\Omega$$
  
$$- \sum_{m \in \Delta_{ijo}} n_m \sum_{e_{pm} \in E(\Delta_{ijo})} \sigma_{pm} \frac{\mu_n E_{pm}}{2} \left[ \coth(a_{pm}) - \sigma_{pm} \right]$$
  
$$\cdot \int_{\Delta_{ijo}} \cap \partial \Omega i \vec{W}_{pm} \cdot \vec{n} dS = - \int_{\Gamma N} h dS - \int_{\Delta_{ijo}} \cap \Omega i R d\Omega$$
(9)

where  $\sigma_{pm} = -1$  if  $e_{pm}$  is oriented from  $v_p$  to  $v_m$ , and  $\sigma_{pm} = 1$  if  $e_{pm}$  is oriented in the opposite direction.

By calculating (9) at all vertices in the mesh cell  $\Delta_{ijo}$ , the matrix form of (9) can be derived as

$$[M_e] \frac{\partial}{\partial t} \{n\} - [K_e] \{n\} = \{f_e\}$$
(10)

where  $K_e$  is the 'upwind' stiffness matrix and its element can be calculated by

$$K_{e,im} = \sum_{e_{pm} \in E(\Delta_{ijo})} \sigma_{pm} \frac{\mu_n E_{pm}}{2} \left[ \operatorname{coth} \left( a_{pm} \right) - \sigma_{pm} \right] \\ \cdot \int_{\Delta_{ijo} \cap \partial \Omega_i} \vec{W}_{pm} \cdot \vec{n} \qquad (11)$$

 $M_e$  is the damping matrix and its element can be calculated by

$$M_{e,im} = \int_{\Delta_{ijo} \cap \Omega_i} N_m \tag{12}$$

 $f_e$  is the column vector and its element can be calculated by

$$f_{e,i} = -\int_{\Gamma N} h \mathrm{d}S - \int_{\Delta i j o \cap \Omega i} R \mathrm{d}\Omega \tag{13}$$

Using the backward difference with respect to time, (10) can be discretized as

$$([M_e] - [K_e]) \{n\}_{t+\Delta t} = [M_e] \{n\}_t + \{f_e\}$$
(14)

where  $\Delta t$  is the time step for time evolution. The system equation for the problem domain can be obtained by summing (14) over all element as [26]

$$([M] - [K]) \{n\}_{t+\Delta t} = [M] \{n\}_t + \{f\}$$
(15)

where [K] is the system 'upwind' stiffness matrix, and [M] is the system damping matrix. This procedure can be easily extended to solve 3-D problems by replacing the control volume in Fig. 1(b) with the control volume composed of tetrahedron inner center, inner center of surface triangular, and center of edge in 3-D mesh cells. For steady-state case, the time-dependent term can be removed, i.e.,

$$-[K] \{n\} = \{f\}$$
(16)

The performance comparison between the improved method and conventional SG method will be given later.

#### **III. MODELING AND SIMULATION SCHEMES**

To verify the performance of our developed FVFEM-SG method, we apply it to a RRAM cell for algorithm evaluation, and further extend it to the large scale parallel simulation platform to solve multiphysics problems in RRAM arrays.

# A. RRAM MODEL

RRAM is a promising candidate for future non-volatile memories due to its fast write/erase speed, large storage density, high efficiency and low power cost. The RRAM cell, shown in Fig. 2, stores information through high resistance state (HRS) and low resistance state (LRS) by rupture and formation of a conduction filament (CF) [27], [28]. HRS and LRS can be switched by an applied voltage.



FIGURE 2. Schematics of (a) 1R RRAM cell and (b) 1D1R RRAM cell with cylindrical CF.

As mentioned above, the ion migration in a RRAM cell can be described by the drift-diffusion equation [18]. The transport of ions should satisfy the continuity equation:

$$\frac{1}{q}\nabla\cdot\vec{J} = \nabla\cdot\left(\mu\left(T\right)n_{D}\vec{E} + D\left(T\right)\nabla n_{D}\right) = \frac{\partial n_{D}}{\partial t} - R$$
(17)

where  $\vec{E} = -\nabla V$ , V is the voltage, and  $\mu(T)$  and D(T) are the temperature-dependent mobility and diffusion coefficient, respectively.

To get the electric field intensity, the current continuity equation needs to be solved,

$$\nabla \cdot (\sigma(n_D, T)\nabla V) = 0 \tag{18}$$

where  $\sigma(n_D, T)$  is the electrical conductivity of the doped dioxide and  $n_D$  is particle concentration.  $\sigma(n_D, T)$  can be given by Arrhenius equation:

$$\sigma(n_D, T) = \sigma_0 \exp\left(-\frac{E_{AC}}{k_B T}\right)$$
(19)

where  $\sigma_0$  is the pre-exponential factor,  $E_{AC}$  is the activation energy for conduction, and  $k_B$  is the Boltzmann constant.

With increasing integration density, self-heating effect (SHE) becomes more and more significant in RRAM arrays which leads to a series of reliability issues, including performance degradation or even breakdown. To capture the temperature distribution due to self-heating, the thermal conduction equation should be solved, i.e.,

$$c(T)\frac{\partial T}{\partial t} = \kappa(n_D, T)\nabla^2 T + Q$$
(20)

where c(T) is the temperature-dependent heat capacity,  $Q = \vec{J} \cdot \vec{E}$  is the heat generation rate, and  $\kappa(n_D, T)$  is the temperature- and particle concentration-dependent thermal conductivity. A nonlinear thermal conductivity model for  $HfO_x$  is specified as [18]

$$\kappa_{\rm HfO} = \kappa_{\rm HfO0} \left( 1 + \lambda \left( T - T_0 \right) \right) \tag{21}$$

where  $\lambda = 0.01$  is the linear thermal coefficient.  $\kappa_{\text{HfO0}}$  is the thermal conductivity at  $T_0 = 300$ K, and it is a function of particle concentration as described in [18].

As seen from (17)–(20), the ion migration and thermal transport are coupled together through temperature- and particle concentration-dependent parameters.

#### **B. NUMERICAL SCHEME**

The flowchart for our proposed numerical algorithm is shown in Fig. 3. It can be seen that the nonlinear particle continuity equation is first solved self-consistently with the current continuity equation to determine the current and particle concentration distributions. From these, the heat generation rate is then calculated and set as an input for the thermal conduction equation. The updated temperature distribution is captured and coupled back to the current and particle concentration continuity equations through the temperaturedependent parameters. In this process, FEM is employed for discretizing the current continuity and thermal conduction equations, while FVFEM-SG method is used to solve the particle continuity equation. After the system matrix equations are obtained, they will be solved using an algebraic multigrid (AMG) solver.



FIGURE 3. Flowchart of the proposed algorithm for electrothermal coupling problems in RRAM.

#### C. PARALLEL SIMULATION

Recently, electrothermal effects in RRAMs have been theoretically investigated [17], [18], using 2-D or small scale 3D array representations [19], [20]. As mentioned above, the electrothermal processes are coupled together, making the simulation much more complicated, time-consuming, especially for large scale RRAM arrays. Consequently, a highperformance parallel multiphysics simulation is urgently required.



FIGURE 4. The generated patches for 512 CPU cores case.

In this context, a double level parallel scheme based on DDM and JAUMIN is employed [23], and simulations can be run on supercomputers with thousands of cores. After reading the mesh, as shown in Fig. 4, JAUMIN generates subdomains (called patches) using the METIS software package [29]. According to the inherent workload distribution scheme, these patches are distributed to every process. To balance the workload of parallel processes and dynamically minimize the number of successive patches assigned to each process, massage passing interface (MPI) parallel programming scheme is utilized. Then, the multi-process and multithread parallel strategy of the DDM is integrated into the JAUMIN framework. One processor generates a process to manage a series of patches and spawns several threads to the CPU cores of the processor. On each CPU core, the sublinear system is formed and then solved individually by AMG solver. In short, the double level parallel scheme improves the simulation process in the following three ways:

- simulate the decomposed subdomains in parallel and independently to accelerate the computation;
- exploit the deeper parallelization of the decomposed subsystems;
- reduce the communication cost significantly among different computer nodes through balanced workload distribution.

Fig. 5 shows the hierarchical structure of the JAUMIN, which is organized into the supporting level, numerical level, and physical level. The supporting layer is composed of the implementation of parallelization, fundamental data structures, and adaptive algorithm. It can provide sufficient support to the other two levels. The physical level acts as a user interface to conduct the discretization of the physical model. The constructed matrices are transferred to the numerical level and then solved. More details of the JAUMIN can be found in [25].

### **IV. RESULTS AND DISCUSSION**

The validity and parallel efficiency of the in-house developed simulator are examined in detail in this section. After that,



FIGURE 5. Hierarchical structure of the JAUMIN.

the simulator is utilized for the analysis of electrothermal characteristics of large scale RRAM arrays.

#### A. FVFEM-SG VS FBSG

As mentioned above, the FVFEM-SG method can overcome the shortcomings of the traditional SG strategy on requirements for meshing grid quality. To better understand this point, a 2-D example is first studied using these two methods on both high-quality and low-quality meshing grids as



FIGURE 6. (a) and (b) Meshing grids for the same structure with different quality, the quality of meshing grid is measured from the color bar where higher value indicates higher quality; (c) and (d) give the particle distributions on high-quality mesh grid achieved by FVFEM-SG and FBSG methods respectively; (e) and (f) illustrate those on low quality mesh grid.

shown in Figs. 6(a) and (b). The simulated results are given in Figs. 6(c)-(f). It can be seen that both methods can achieve decent results for high-quality mesh grid while the FBSG results for low-quality mesh grid are distorted. Consequently, the FVFEM-SG method is deemed as a better choice for discretizing the RRAM like models.

#### **B. ALGORITHM VALIDATION**

The accuracy of our developed algorithm is validated through comparison with both experimental data [18] and commercial software. As shown in Fig. 2(a), one-resistor (1R) RRAMs with cylindrical CFs is taken as an example. According to [18], the CF is formed in the HfO<sub>2</sub> layer, which is sandwiched between the top and bottom electrode (ETD). The geometrical and physical parameters of the 1R RRAM cell are summarized in Table 1. The I-V and R-V curves of 1R cell in Fig. 7 are obtained by applying a triangular voltage sweep with ramp rate 1.1 V/s. It is evident that the simulated results using the in-house developed simulator agree well with the experimental data adopted from [18]. Further, the COMSOL Multiphysics is used to verify the accuracy of the in-house developed simulator by simulating a one-diode-one-resistor (1D1R) RRAM cell (see Fig. 2(b)). Table 2 gives the geometrical parameters of the 1D1R RRAM cell. As shown in Fig. 8, the results obtained by COMSOL Multiphysics and the in-house developed simulator are in good agreement with each other. The insets of Figs. 8(b) and 8(c) show the distributions of temperature and particle concentration along the CF.



**FIGURE 7.** I-V and R-V characteristics of RRAM cell with CF diameter of 9 nm. The voltage was increased according to a triangular sweep with ramp rate 1.1 V/s.

 TABLE 1. Geometrical and physical parameters of the 1R RRAM cell.

Comp.	Materials	Geometrical parameters	Physical parameters
CF	HfO <sub>2</sub>	$r_{\rm CF} = 4.5 \ { m nm}$ $h_{ m CF} = 20 \ { m nm}$	$\kappa_{ m CF}$ : Eq. (21) $c_{ m CF} = 445$ J/kg°C $\sigma_{ m CF}$ : Eq. (19)
Cell Via Hole	HfO <sub>2</sub>	$r_{\rm CVH} = 35 \text{ nm}$ $h_{\rm CVH} = 20 \text{ nm}$	$k_{\text{CVH}} = 0.5 \text{ W/(m \cdot \text{K})}$ $c_{\text{CVH}} = 445 \text{ J/kg}^{\circ}\text{C}$ $\sigma_{\text{CVH}}$ : Eq. (19)

#### TABLE 2. Geometrical parameters of the 1D1R RRAM cell.

Comp. Materials		Geometrical parameters		
B/W Line	Ni/Pt	$w_{ m etd} = 80 \  m nm$ $h_{ m etd} = 25 \  m nm$		
CF	HfO <sub>2</sub>	$r_{\rm CF} = 8 \text{ nm}$ $h_{\rm CF} = 80 \text{ nm}$		
Cell Via Hole	HfO <sub>2</sub>	$r_{\rm CVH} = 80 \text{ nm}$		
Diode	Ti/TiO <sub>2</sub> /Pt	$r_{\rm d} = 40 \text{ nm}$ $h_{\rm d} = 50 \text{ nm}$		



FIGURE 8. Comparison of simulation results between the in-house simulator and COMSOL in which a voltage source with ramp rate 1.1V/s is applied onto the top electrode. (a) Maximum temperature in the RRAM cell as a function of time, and the distributions of (b) temperature and (c) particle concentration along the cylindrical axis of the RRAM cell at 0.5 s.

# C. SPEEDUP & SCALABILITY

Two indices, *speedup* and *scalability*, are typically used to evaluate the performance of parallel simulator [25]. The *speedup* which shows performance improvement in time cost with respect to problem size and core number, is defined as:

$$S = \frac{T(N_{core})}{T(M_{core})} \cdot \frac{Size(M_{core})}{Size(N_{core})}$$
(22)

where  $T(\cdot)$  represents the Wall time (I/P/PDDM), *Size*( $\cdot$ ) is the problem size which can be described by the degree of freedom. In (22), the case of  $N_{core}$  is taken as reference.

The *scalability* represents the scaling tendency of parallel algorithm with increasing number of cores or problem size.

$$\Phi = \frac{S}{M_{core}/N_{core}} \tag{23}$$



**FIGURE 9.** Schematic of the SBL cross-bar RRAM array with 512 cells (8 × 8 × 8). The golden strips represent the electrodes, blue cylinders are conduction filaments, and red and green cylinders represent the diodes at off and on states, respectively.

As shown in Fig. 9, a 512-cell ( $8 \times 8 \times 8$ ) cross-bar RRAM array is taken as an example for parallel computing [27], [28]. The geometrical parameters of a one-diodeone-resistor (1D1R) RRAM cell are listed in Table 2. The cells in the array are randomly programmed, and the detailed power supply scheme is given in Table 3, where 0, 1, and -1 are the bias states for electrodes, representing dangling, high voltage and ground, respectively. A voltage sweep with ramp rate 1 V/s is applied to the biased electrode and the time step is chosen to be 0.01 s in the simulation.

TABLE 3. The states of each electrode in the RRAM array with 512 cells.

	S	S	S	s	S	s	s	s
ETD 1	0	0	1	0	0	0	0	0
ETD 2	0	0	-1	0	0	0	0	0
ETD 3	0	0	0	1	0	0	0	0
ETD 4	0	0	0	0	-1	0	0	0
ETD 5	0	0	1	0	0	0	0	0
ETD 6	0	0	-1	0	0	0	0	0
ETD 7	0	0	0	0	0	0	1	0
ETD 8	0	0	0	-1	0	0	0	0
ETD 9	0	0	0	1	0	0	0	0

Here, both the strong scalability and weak scalability of the in-house developed simulator are investigated. For the strong case, the degree of freedom is fixed at 47 470 182 and the simulated results are presented in Fig. 10(a) and Table 4. As given in Fig. 10(a), our algorithm can reach a *Speedup* of



FIGURE 10. Scalability analysis on TianHe-II supercomputer. (a) Strong scalability and (b) weak scalability.

#### **TABLE 4.** Strong scalability experiment.

Number of DOFs (million)	Number of node/core/ process	Average CPU time per step (s)	Total nonlinear iterations	Total solver iterations
	8/64/64	871.086	305	24589
47 47	16/128/128	489.669	305	27830
47.47	32/256/256	346.622	305	29332
	64/512/512	283.749	305	33135

3.07 and strong scalability efficiency of 38.37% on 512 CPU cores of 128 compute nodes, starting from 64 CPU cores of 16 compute nodes. Fig. 10(b) and Table 5 show the weak scalability results, in which 32.05% parallel efficiency is still achieved with a 64-fold increase in the problem size from 746 624 to 47 470 182, and computing resources from 8 CPU cores of 4 compute nodes to 512 CPU cores of 128 compute nodes. In Fig. 11 the simulated results of 47 470 182 size problem using 512 cores is given as an example. The drop in parallel efficiency with increasing problem size is mainly due to the following reasons:

- For strong scalability, the time consumed by the AMG solver increases from 39.92% to 51.66% as the number of CPU cores increases from 64 to 512, implying that the solver will be less efficient when the size of the problem (matrix size) becomes smaller.
- 2) As given in Table 5, there are about 30% and 52% growth in the number of total solver iterations in the cases of 64 and 512 CPU cores compared with that of 8 CPU cores, respectively. As the patch number increases, the geometry size of each patch becomes smaller, thereby increasing the dependency between adjacent patches. In other word, more iterations are



FIGURE 11. (a) Particle density and (b) temperature distributions in the 512-cell RRAM array at t=0.4s.

Number of DOFs (million)	Number of Node/Core/ Process	Average CPU time per step (s)	Total nonlinear iterations	Total solver iterations
0.75	1/8/8	85.241	296	21816
5.94	8/64/64	143.310	300	28302
47.47	64/512/512	283.749	305	33135

TABLE 5. Weak scalability experiment.

required to achieve convergent global solution for one governing equation.

3) The increase in the number of patch and boundary increases the time consumed in the information exchange between the cores, thereby resulting in the decreased efficiency.

#### D. THERMAL CROSSTALK AND RELIABILITY ANALYSIS

In the highly integrated RRAM array, RRAM cell can be affected by adjacent cells, which degrades reliability or even may change its stored information. In this subsection, we carefully investigate the electrothermal effect in RRAM array, and the reliability problem induced by thermal crosstalk effect.



**FIGURE 12.** (a) Schematic of the SBL cross-bar RRAM array with 100 cells (5 × 5 × 4), in which four cells of the second layer marked in green are activated and (b) cross section of the second layer (k=2) of the RRAM array. Green and red represent the active and inactive cells, respectively.

Fig. 12(a) shows a shared-bit-line (SBL) cross-bar RRAM array with 100 cells ( $5 \times 5 \times 4$ ), each cell in RRAM array is with the same geometrical parameters as in Table 2. The cross section of the second layer (counted from the bottom) is depicted in Fig. 12(b). The cells in the array are denoted by  $(ij)_k$ , where *i*, *j*, and *k* represent the index number along the x-, y-, and z-directions, respectively. According to the power supply scheme in Table 6, four cells of the second layer are activated by injecting a rectangular pulse with amplitude of 1.2 V. All the other cells in the array are inactive.

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 TABLE 6. The bias states of electrodes in RRAM array with 100 cells.



**FIGURE 13.** 3D (a) temperature and (b) particle density distribution of the SBL RRAM array sliced through the center of cells  $(22)_k$  along both *x*- and *y*-directions.

Fig. 13 presents the simulated results in sliced planes through the center of cell  $(22)_k$  along both x- and y-directions. To better understand the simulated results, temperature and particle density distribution along z-axis through certain cells are extracted and plotted in Figs. 13 (a) and (b), respectively. It is shown that three victim cells around the cell  $(22)_2$ , i.e.,  $(23)_2$ ,  $(32)_2$ , and  $(33)_2$ , are affected to various extents. The maximum temperatures of these victim cells reach 617.2 K at  $z = 0.292 \mu m$ , 592.9 K at  $z = 0.275 \mu m$ , and 533.6 K at  $z = 0.306 \mu m$ , respectively. The cell  $(33)_2$ exhibits the lowest crosstalk temperature among these victim cells, as it has a large distance to the active cells. Although the cells  $(23)_2$  and  $(32)_2$  have the same distance to the active cells, the cell  $(23)_2$  suffers from larger crosstalk temperature due to the asymmetric structure of electrodes, which will be discussed in detail in the next paragraph. The resistance ratios (to the initial value) of the CFs of cells  $(22)_k$ ,  $(23)_k$ ,  $(32)_k$ , and  $(33)_k$  are shown in Fig. 14(c). It can be seen that the resistance ratio of the victim cell  $(23)_2$  can reach greater than 2, which may cause loss of the stored information [18].

To explain the related in detail, an equivalent thermal resistance networks are established as in Fig. 15. The thermal conductivity of HfO<sub>x</sub> is expressed as  $\kappa_{\rm HfO} = a \cdot n_D + b$ , where  $a = 1.875 \times 10^{-26} \text{W} \cdot \text{m}^2/\text{K}$ ,  $b = 0.5 \text{W/m} \cdot \text{K}$  and  $n_D$  is the particle density (in m<sup>-3</sup>). Here, the background density  $n_D$  in HfO<sub>x</sub> is set to be  $1 \times 10^{22} \text{m}^{-3}$ , and  $\kappa_{\rm HfO}$  is calculated as  $0.5 \text{W/m} \cdot \text{K}$ , which is much smaller than that of the metal electrode. Hence, the metal electrode has much low thermal resistance compared to HfO<sub>x</sub>. Heat dissipates more effectively in thermal resistance network (a) than (b). Therefore, the cell (23)<sub>2</sub> suffers from severer thermal crosstalk than the cell (32)<sub>2</sub>, which is consistent with the results in Fig. 14(a).



**FIGURE 14.** (a) Temperature distribution, (b) particle density distribution, and (c) resistance ratio of the SBL RRAM array with 100 cells along the *z*-axis through centers of the cells  $(22)_{k'}$ ,  $(23)_{k'}$ ,  $(32)_{k}$ , and  $(33)_{k}$ .

The effects of various structural parameters, including the radius of cylindrical CF, and the cell size, on the thermal crosstalk in the victim cell  $(23)_2$  are further studied.

#### 1) RADIUS

Fig. 16 shows the temperature distribution of the RRAM array along the *z*-direction through the center of victim cell  $(23)_k$ . As the radius of CF increases from 6 nm to 10 nm, the maximum crosstalk temperature increases from 580.2K to 650.6 K. This is due to the fact that decreasing the radius increases the CF resistance, thereby suppressing the power consumption and SHE in the RRAM array. Fig. 17 shows the 3D temperature distributions of the CRRAM arrays for different  $r_{cf}$ . However, the decrease in the power will degrade the switching performance of the RRAM cells, which is reflected by the variation of the resistance ratio (see Fig. 18).

It can be seen from Fig. 18 that the thermal crosstalk has a negligible influence on the resistance ratio of victim cell  $(23)_2$  as  $r_{cf} = 6$ nm, and it becomes more significant as



**FIGURE 15.** Particle density distribution sliced through the center of cell (22) along the (a) *x*- and (b) *y*-directions and the corresponding thermal resistance networks.



**FIGURE 16.** Steady-state temperature distribution of the RRAM array along the *z*-direction through the center of cell  $(23)_k$  with different  $r_{cf}$ .



**FIGURE 17.** 3D temperature distribution of the RRAM array sliced through the center of (22) along both x- and y-directions with (a)  $r_{cf} = 6$ nm and (b)  $r_{cf} = 10$ nm.

 $r_{cf}$  increases, which is similar to the variation tendency of the crosstalk temperature shown in Fig. 16. As explained earlier, the larger the CF radius, the higher the power consumption,



**FIGURE 18.** Resistance ratio of the cells  $(22)_k$  and  $(23)_k$  with different  $r_{cf}$  in the RRAM array.

and consequently, the sharper the temperature rise in the programmed cell. This phenomenon is also reflected by the variation of the resistance ratio of the cell  $(22)_2$ , as shown in Fig. 18. Furthermore, the 3D particle density distribution of the RRAM arrays with  $r_{cf}$  of 6 nm and 10 nm are plotted in Fig. 19.



**FIGURE 19.** 3D particle density distribution of the RRAM array sliced through the center of cell (22) along both x- and y-directions with (a)  $r_{cf} = 6$ nm and (b)  $r_{cf} = 10$ nm.

### 2) CELL SIZE

The effects of cell size on the thermal crosstalk are investigated. Fig. 20 shows the temperature along the *z*-direction through the center of victim cell  $(23)_k$ . As  $p_{cell}$  increase



**FIGURE 20.** Temperature distribution of the RRAM array along the *z*-direction through the center of cell  $(23)_k$  with different  $p_{cell}$ .



**FIGURE 21.** 3D temperature distribution of the RRAM array sliced through the center of the cells  $(24)_k$  along both *x*- and *y*-directions with (a)  $p_{cell} = 150$ nm, and (b)  $p_{cell} = 170$ nm.



FIGURE 22. Resistance ratio of the cells  $(22)_k$  and  $(23)_k$  in the RRAM array with different  $p_{cell}$ 



**FIGURE 23.** 3D particle density distribution of the RRAM array sliced through the center of cell  $(22)_k$  along the *x*- and *y*-direction with (a)  $p_{cell} = 150$ nm, and (b)  $p_{cell} = 170$ nm.

from 150 nm to 170 nm, the maximum crosstalk temperature decreases slightly from 624.7 K to 610 K, which is due to the decrease of power density. Fig. 21 shows the 3D temperature distribution of the RRAM arrays with different  $p_{cell}$ .

The resistance ratio of the cells  $(22)_k$  and  $(23)_k$  with different  $p_{cell}$  are shown in Fig. 22. It can be seen that as  $p_{cell}$  increases from 150 to 170 nm, the resistance ratio of the cell  $(23)_2$  decreases from 3.42 to 2.41 due to the decrease of temperature. The 3D particle density distribution of the RRAM arrays with  $p_{cell}$  of 150 nm and 170 nm are plotted in Fig. 23.

#### **V. CONCLUSION**

In this paper, FVFEM-SG method is developed for solving the continuity equation for diffusive transport in electronic devices. The algorithm stability is improved over the traditional FBSG method, especially in the condition of low meshing quality. A high performance parallel-computation simulator based on the domain decomposition method and J parallel adaptive unstructured mesh applications infrastructure is developed for large scale electrothermal simulation of resistive random access memory (RRAM) arrays, in which the FVFEM-SG is used to solve the ion migration process. Speedup and scalability of the parallel algorithm up to 512 computer cores are investigated on supercomputer TianHe-2. The effects of various structural parameters, including conductive filament (CF) radius, and cell size, on the electrothermal characteristics of RRAM arrays are captured and studied.

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